

Proton Radiation Effects in Tin Oxide Thin-Film Transistors with Different Device Structures

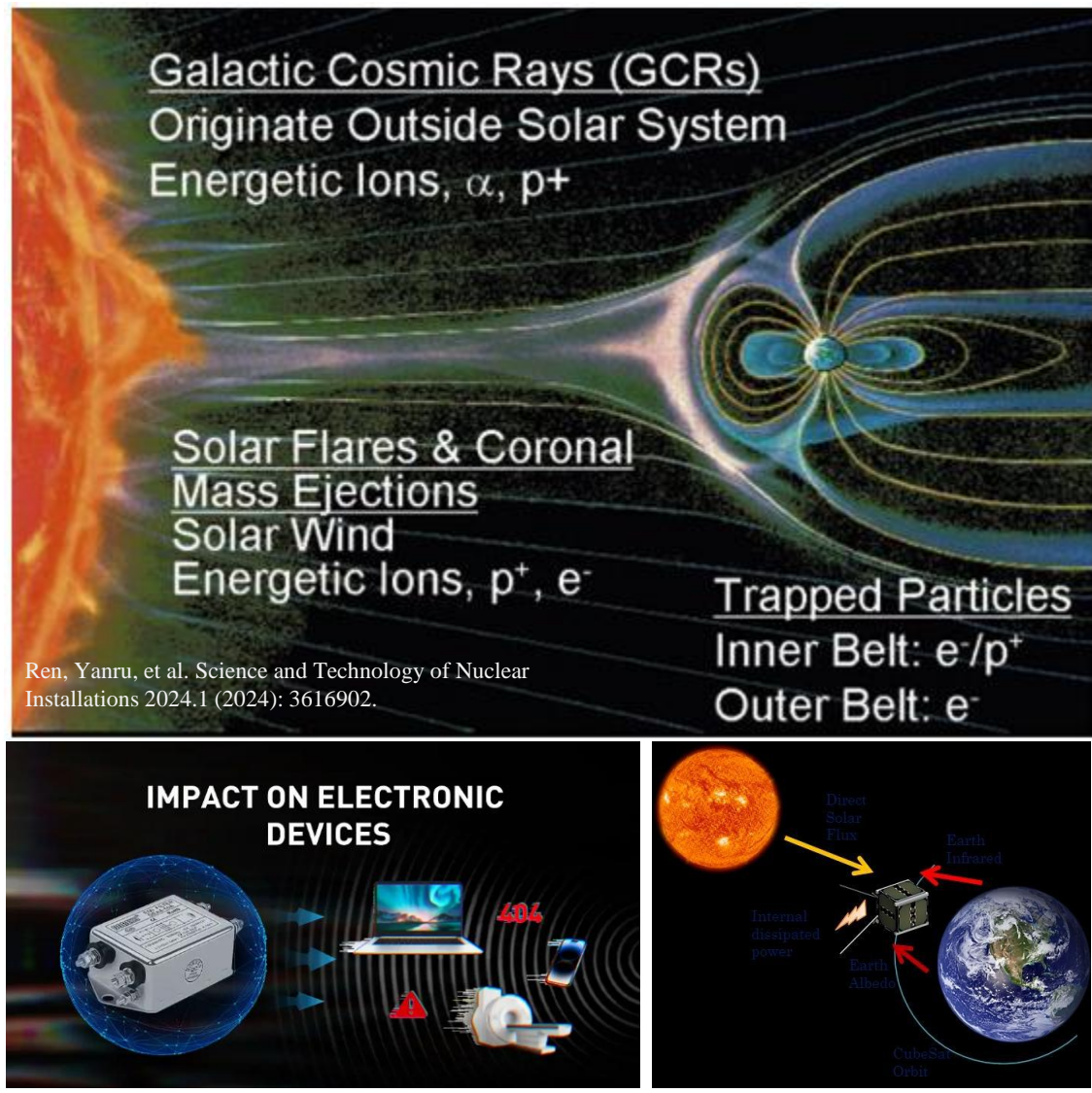
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Introduction

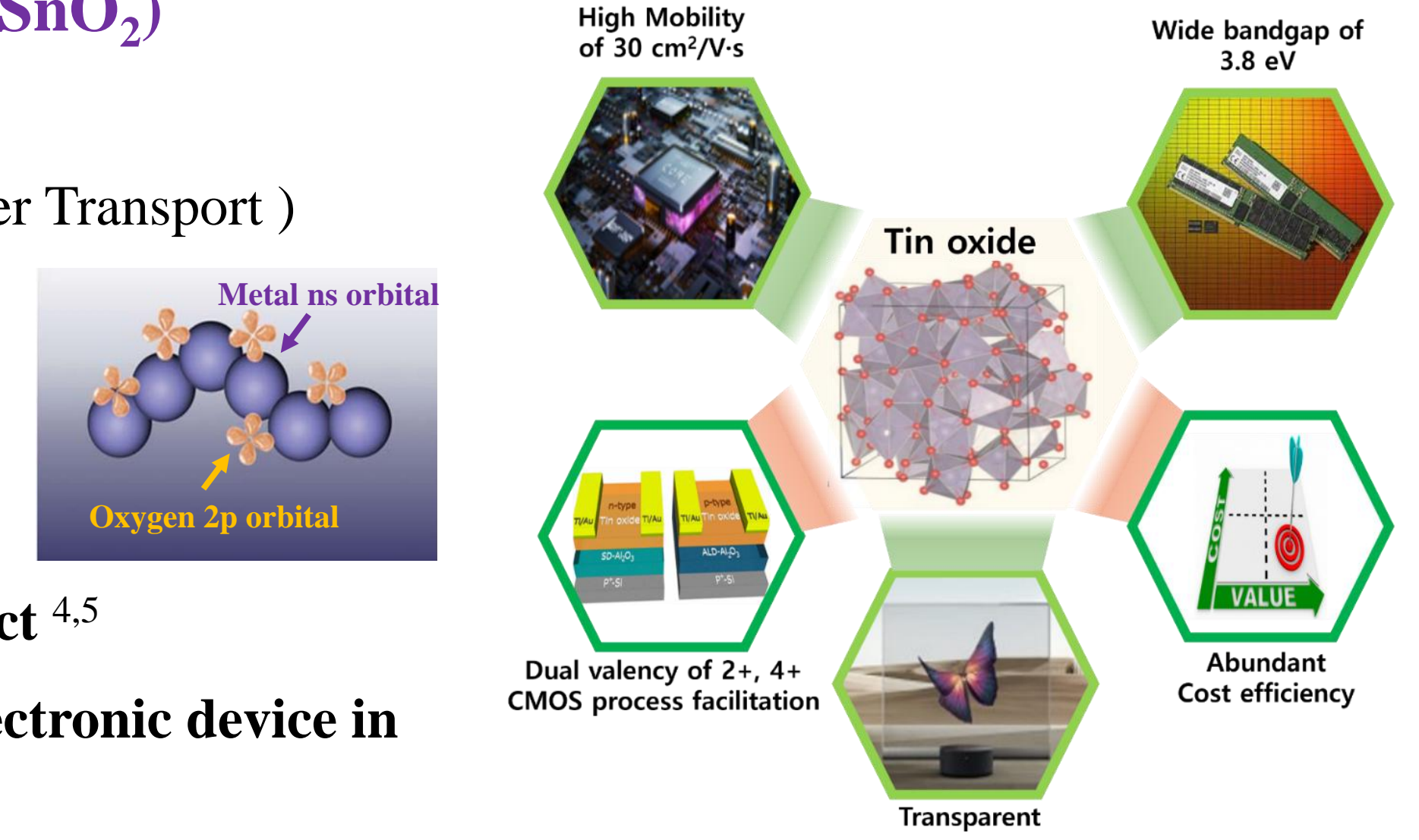


Space Radiation Environment

- Galactic Cosmic Rays (GCRs), Solar Particle Event (SPEs) : **Proton**, He ion, electron, heavy ions
- Van Allen Radiation Belts : trapped particle (**Proton**, α -particles, electron) by two main belts (640–58,000 km)
- These radiation particles affect the semiconductor with DD (Displacement Damage), TID (Total Ionizing Dose), SEE (Single Event Effect) ^{1,2}.
- About 30% of electronics anomalies in space are attributed to radiation effect ³.

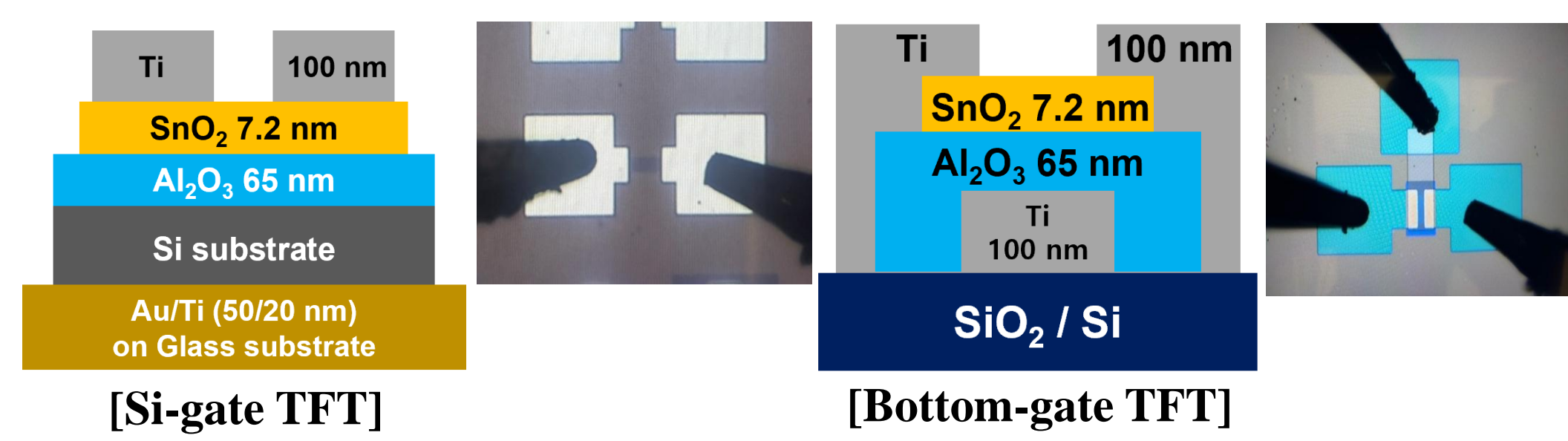
Advantages of Tin Oxide (SnO₂)

- s-orbital conduction**
 - Defect-tolerant (Stable Carrier Transport)
- Wide bandgaps**
 - Suppresses leakage current
 - Strong M-O bonds
- **Resistant to DD and TID effect** ^{4,5}
- **SnO₂ can be utilized as an electronic device in the aerospace field**

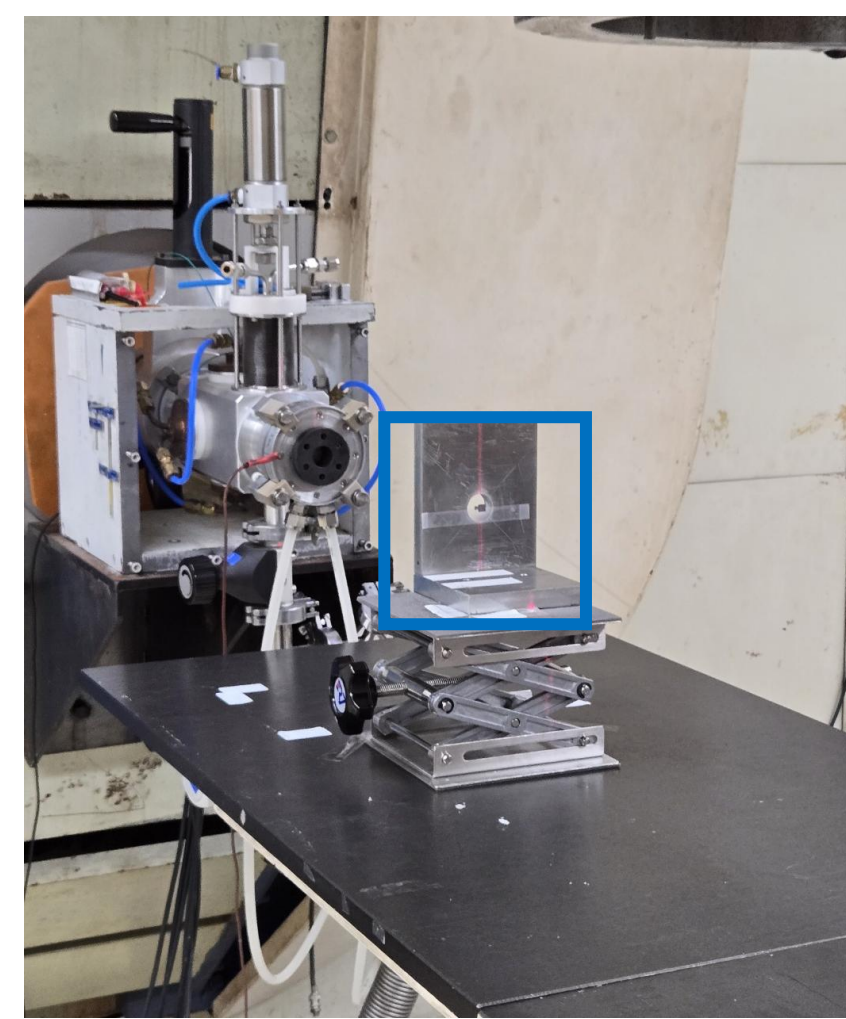


Experiments

SnO₂ TFTs with different structures

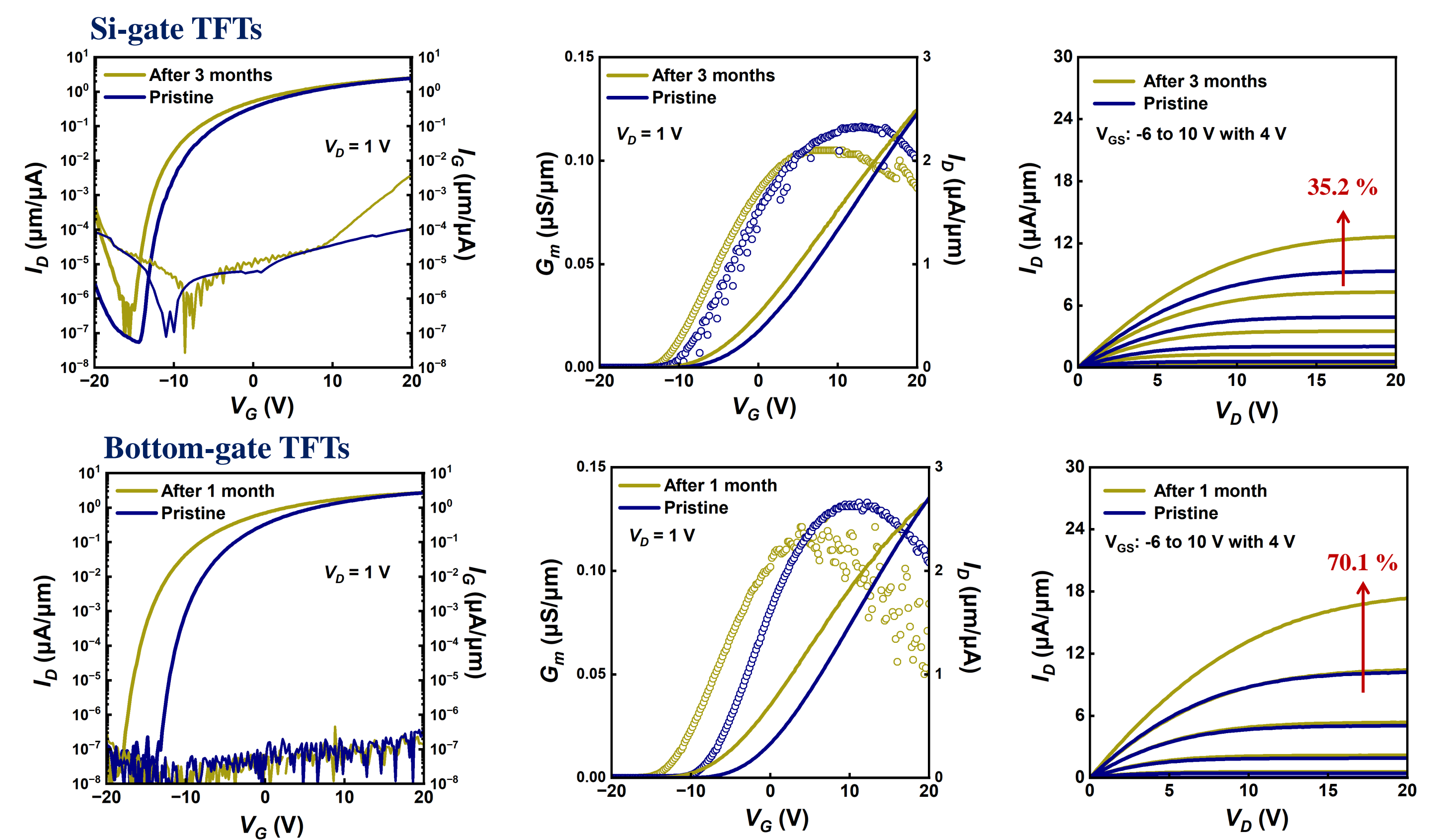


- Si-gate TFT**: A structure using a Si-substrate as the bottom gate, forming an SnO₂ channel without Al₂O₃ (dielectric) etching.
- Bottom-gate TFT**: In a conventional TFT structure, after forming individual gate (Ti), SnO₂ channels are formed following Al₂O₃ etching.
- Irradiation was performed using a **5 MeV proton beam** supplied by an MC-50 cyclotron at KIRAMS. The device samples were exposed to **fluences of 1 × 10¹⁴ cm⁻²**.



Device performance after aging in room-temperature

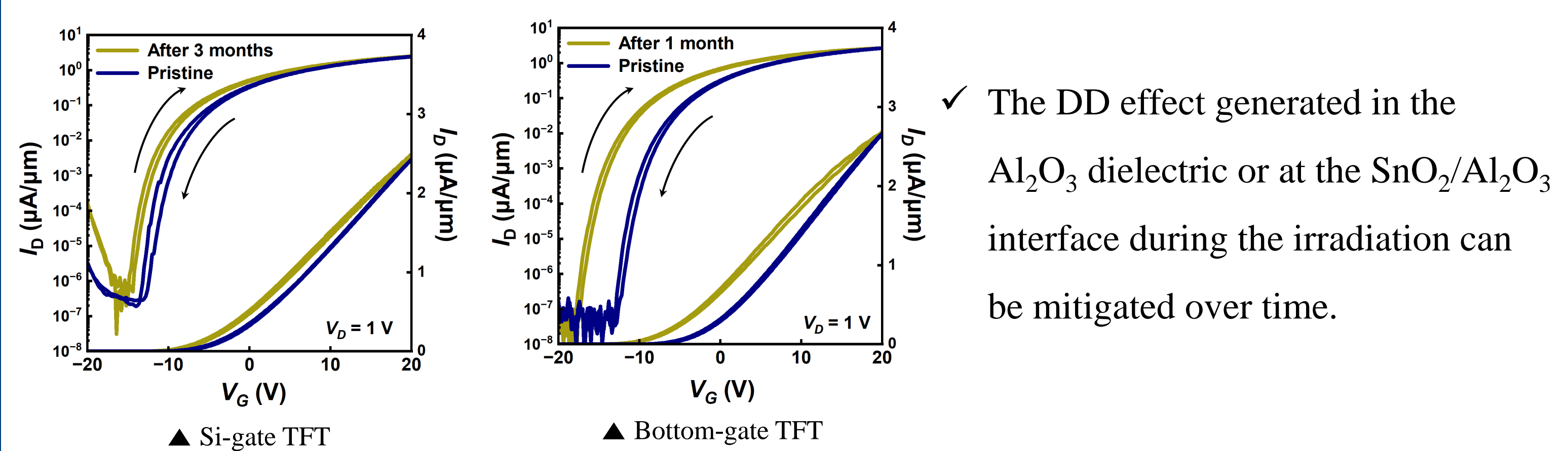
I-V characteristics of SnO₂ TFTs after aging in room temperature



- After aging in room-temperature (RT), the both devices mitigated toward pre-irradiation states, with the Si-gate TFT exhibiting more pronounced mitigation.
- In addition, the leakage current (I_G) of the bottom-gate TFTs decreased to level a comparable to that after irradiation.

Dual-sweep transfer characteristics after aging in RT

The hysteresis curves showed a tendency to return to their pre-irradiation states. (exhibiting a clockwise hysteresis curve)

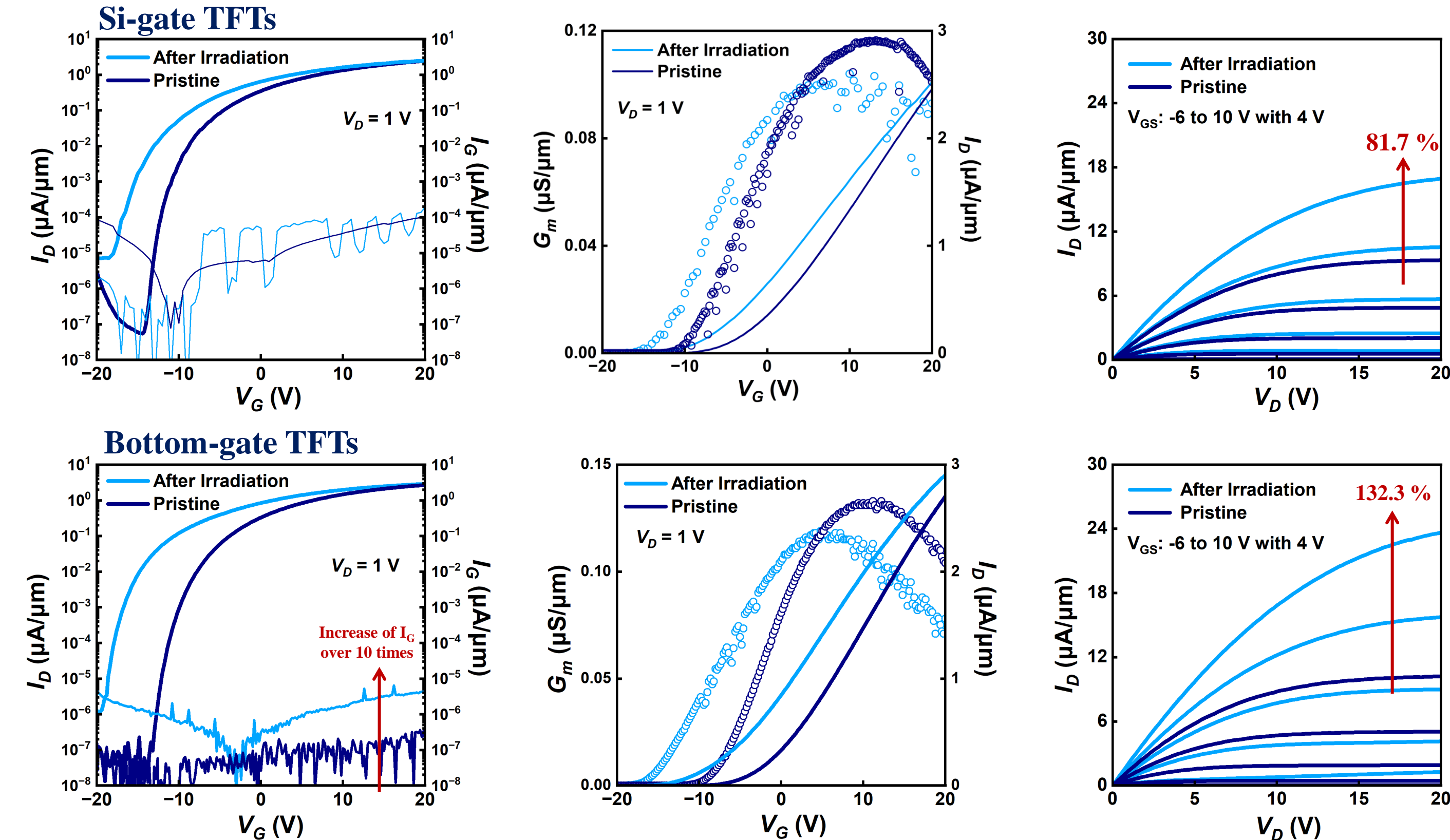


Summary of the device parameters

	Conditions	V_{th} [V]	μ_{FE} [cm ² /Vs]	SS [V/dec]	$I_{on/off}$
Si-gate TFT	Pristine	-2.73	17.30	0.86	4.48×10^7
	Proton Irrad.	-6.67	15.44	1.03	3.60×10^5
	After Aging	-4.80	15.64	0.73	5.33×10^6
Bottom-gate TFT	Pristine	-1.95	19.73	0.93	2.87×10^7
	Proton Irrad.	-8.81	17.64	0.85	2.47×10^6
	After Aging	-6.44	18.00	0.97	8.51×10^7

Device performance after proton irradiation

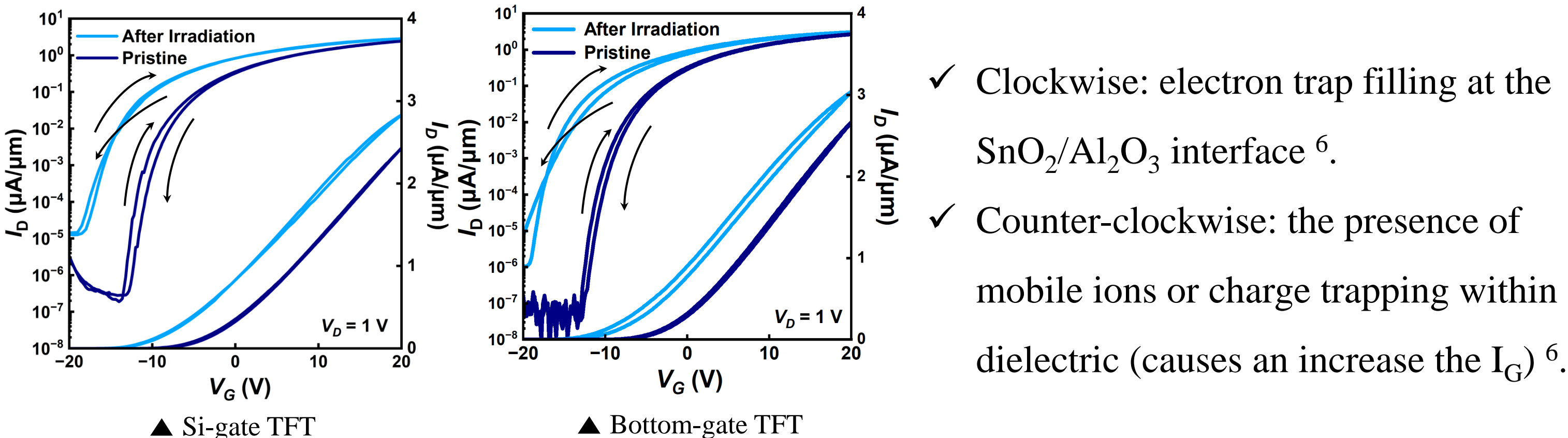
I-V characteristics of SnO₂ TFTs after proton irradiation



- After proton irradiation, both devices exhibited a negative shift in the threshold voltage (V_{th}) and an increase in the output current (I_D).
- Increases in the carrier concentration in the channel induced by proton irradiation (**DD effect**).

Dual-transfer characteristics after proton irradiation

Hysteresis curves in the form of a mixture of clockwise and counter-clockwise was confirmed.



- ✓ Clockwise: electron trap filling at the SnO₂/Al₂O₃ interface ⁶.
- ✓ Counter-clockwise: the presence of mobile ions or charge trapping within dielectric (causes an increase the I_G) ⁶.

Conclusion

- Proton irradiation induced a negative V_{th} shift and increased I_D in both SnO₂ TFTs structures, indicating increased channel conductivity after irradiation due to DD effect.
- The irradiated-SnO₂ TFTs after aging in room-temperature, both devices showed a tendency to return to their pre-irradiation state, which was particularly pronounced in the Si-gate TFT.
- The dual-sweep I-V results indicated the DD effect caused by irradiation on the dielectric, which suggests the possibility that it caused an increase in leakage current (I_G) in the bottom-gate TFT.

References & Acknowledgment

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